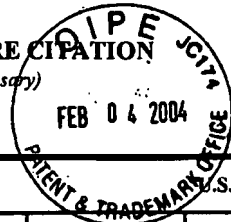


**INFORMATION DISCLOSURE CITATION**  
(Use several sheets if necessary)



Docket Number (Optional)  
**OKA-C387**

Application Number  
**10/743,314**

Applicant(s)  
**Reiko WATANABE**

Filing Date  
**12/23/03**

Group Art Unit

**U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE: IF APPROPRIATE
/MTE/		5,879,459	3/9/99	GADGIT et al	118	715	
/MTE/		6,174,377	1/16/01	DOERING et al	118	729	
/MTE/		6,387,185	5/14/02	DOERING et al	118	729	

**FOREIGN PATENT DOCUMENTS**

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
/MTE/		2002-4054	1/9/02	JP				
/MTE/		2001-348666	12/18/01	JP				

**OTHER DOCUMENTS** (Including Author, Title, Date, Pertinent Pages, Etc.)

/MTE/		Handbook of Thin Film Process Technology, B1.5:1-B1.5.17, 1995 IOP Publishing Ltd.

EXAMINER /Matthew Eggerding/

DATE CONSIDERED 07/24/2007

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.